

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)
Shinji MAEKAWA et al.) Confirmation No. 3788
Application No. 10/575,492) Examiner: Stanetta D. Isaac
Filed: April 12, 2006) Group Art Unit: 2812
For: METHOD FOR FORMING WIRING, METHOD)
FOR MANUFACTURING THIN FILM) Date: February 3, 2009
TRANSISTOR AND DROPLET DISCHARGING)
METHOD)

RESPONSE TO FINAL OFFICE ACTION

Mail Stop: RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated November 3, 2008, Applicants respectfully request reconsideration and allowance of the above-identified application based on the following amendments and remarks. A request for continued examination under 37 C.F.R. § 1.114, including the fee set forth by 37 C.F.R. § 1.17(e), is being filed concurrently herewith. Accordingly, Applicants request the entry, and examination of the following amendment and remarks.